

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 245583US0S DIV		SERIAL NO. New Application	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Satoshi MATSUDA, et al.			
				FILING DATE Herewith		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
<i>JH</i>	AA	6,518,155	02-03	CHAU, ET AL.			
<i>JH</i>	AB	6,573,583	06-03	HOKAZONO			
<i>JH</i>	AC	6,127,707	10-00	CHONG, ET AL.			
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO			
<i>JH</i>	AO	411274320A	10-99	JAPAN			
<i>JH</i>	AP	2002-110817	04-02	JAPAN			X
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
<i>JH</i>	AW	Yasuhiro SATO, et al., "Study of HF-Treated Heavily-Doped Si Surface Using Contact Angle Measurements", JPN. J. APPL. PHYS., Volume 33, December 1994, Pages 6508-6513.					
<i>JH</i>	AX	Toshihiko KOSUGI, et al., "Effects of Hydrogenation of Hydrogen Termination of p ⁺ -silicon (100) Surfaces by Hydrofluoric Acid", J. VAC. SCI. TECHNOL. A15(1), Jan/Feb 1997, Pages 127-132.					
<i>JH</i>	AY	Yoshihiro SUGITA, et al., "Influence of Microscopic Chemical Reactions on the Preparation of an Oxide-Free Silicon Surface in a Fluorine-Based Solution", JPN. J. APPL. PHYS., Volume 38, 1999, Pages 2427-2433.					
	AZ						
				<input type="checkbox"/> Additional References sheet(s) attached			
Examiner <i>Gymne A. Hurley</i>				Date Considered <i>9/3/04</i>			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							